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## IN THE CLAIMS:

Please amend claims 7, 11, 14, and 15, as follows:

1-6. (Previously Cancelled)

7. (Presently Amended) A method for making a high fill factor image array comprising the steps:

providing a plurality of source-drain metal contacts;

depositing a first passivation layer;

depositing a second passivation layer that suppresses lateral leakage current;

opening a plurality of via holes through the first and second passivation layers;

depositing a layer of conductive material;

depositing a first doped a-Si layer;

patterning to form [the] collection electrodes;

depositing a continuous layer of i a-Si;

depositing a continuous second layer of doped a-Si;

depositing and patterning an upper conductive layer.

- 8. (Original) The method for making a high fill factor image array according to claim 7, wherein the first passivation layer comprises silicon oxynitride, BCB, or a polyamide.
- 9. (Original) The method for making a high fill factor image array according to claim 7, wherein the second passivation layer is an oxide.

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- 10. (Original) The method for making a high fill factor image array according to claim 7, wherein the second has a thickness of about 1000 Å.
  - 11. (Presently Amended) A high fill factor image array formed by: providing a plurality of source-drain metal contacts; depositing a first passivation layer;

depositing a second passivation layer over the first passivation layer that suppresses lateral leakage current;

opening a plurality of via holes through the first and second passivation layers; depositing a layer of conductive material; depositing a first doped a-Si layer; patterning to form [the] collection electrodes; depositing a continuous layer of a-Si; depositing a continuous second layer of doped a-Si; depositing and patterning an upper conductive layer.

- 12. (Original) The high fill factor image array of claim 11, wherein the first passivation layer comprises at least one of silicon oxynitride, BCB, or a polyamide.
- 13. (Original) The high fill factor image array of claim 11, wherein the second passivation layer is an oxide.

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14. (Presently Amended) The high fill factor image array of claim 11, wherein the second <u>passivation layer</u> has a thickness of about 1000 Å.

15. (Presently Amended) The high fill factor image array of claim 11, wherein a [the wherein the] thickness of the second passivation layer is less than a [the] thickness of the first passivation layer.

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